

METHOD OF FORMING SILICON-CONTAINING INSULATION  
FILM.....  
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Appl. No.: Unknown Atty Docket: ASMJP.137AUS

Fig. 1

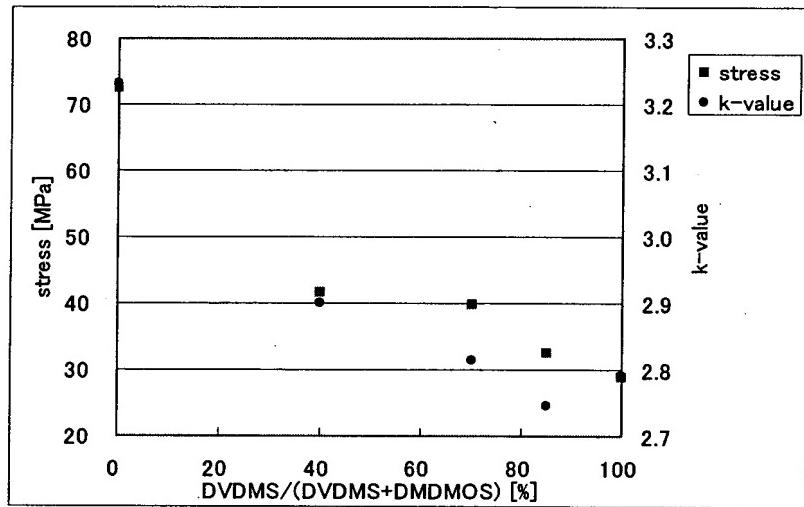


Fig. 2

